

METHOD OF DOUBLE-SIDED ETCHING

Appl. No. : 10/711,883 Confirmation No. 5882
Applicant : Chen-Hsiung Yang
Filed : October 12, 2004
TC/A.U. : 1765
Examiner : CHEN, KIN CHAN
Docket No. : TMIP0003USA
Customer No. : 27765

Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

AMENDMENT

5 In response to the Office action of November 02, 2006, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.